Docket No. N1085-00160
Inventors: Wen-Chuan Wang et al.
"System And Method For Examining Mask Pattern Fidelity"
Sheet 1 of 3

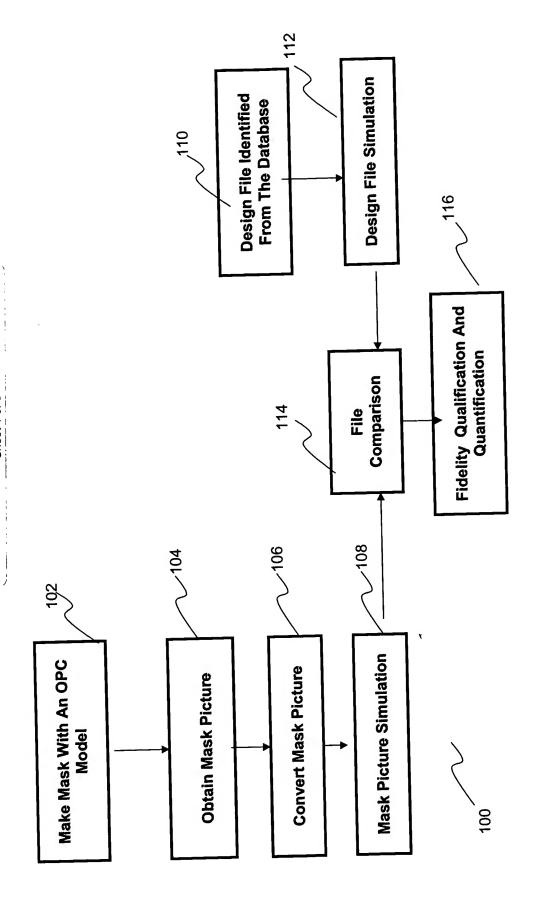


FIG.

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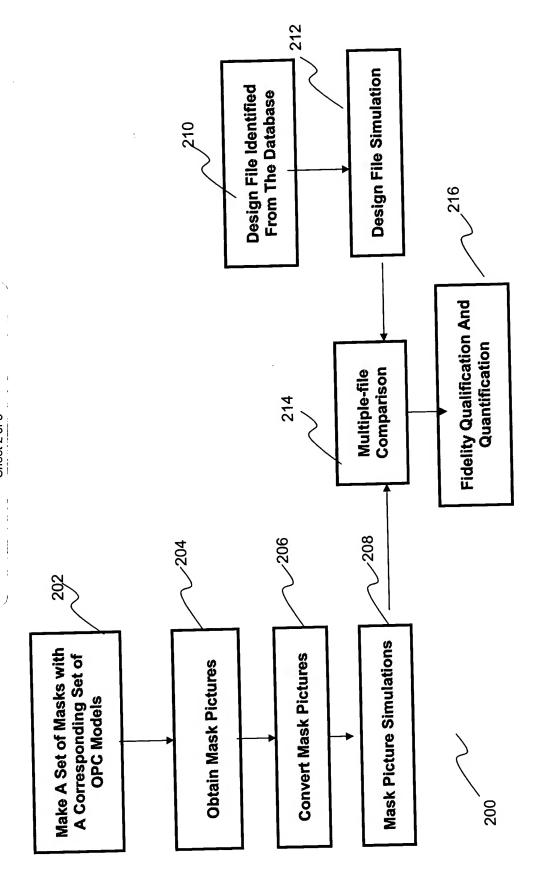


Fig. 2

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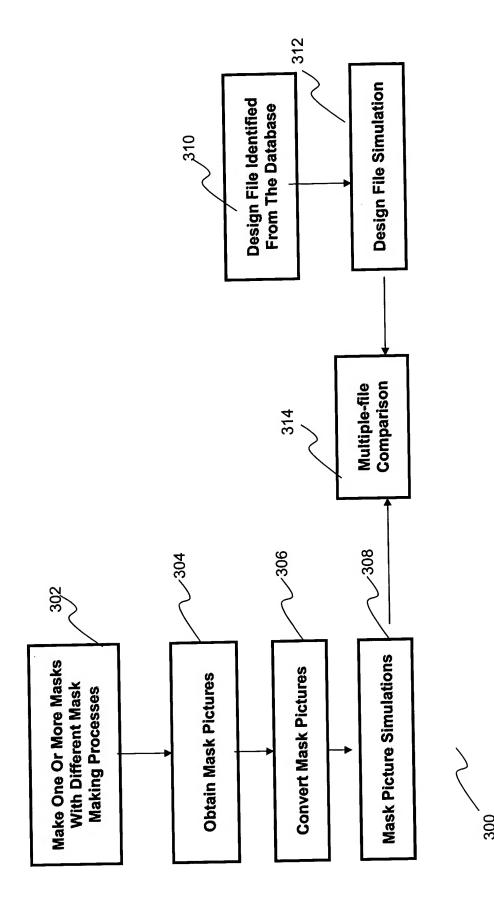


Fig. 3